

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/813,543
Filing Date March 30, 2004
Confirmation No. 8087
Inventor F. Dan Gealy
Assignee Micron Technology, Inc.
Group Art Unit 1792
Examiner Keath T. Chen
Attorney's Docket No. MI22-3685
Title: Method for Reducing Physisorption During Atomic Layer Deposition

RESPONSE TO AUGUST 1, 2008 FINAL OFFICE ACTION

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